Method For Forming Raised
Structures by Controlled Selective Epitaxial
Growth of Nacet Using Pacer
Atty. Docket No. MTI-31041-A

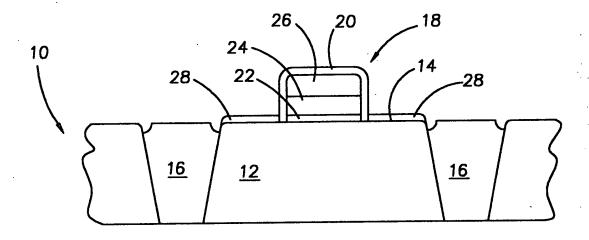


FIG.1A

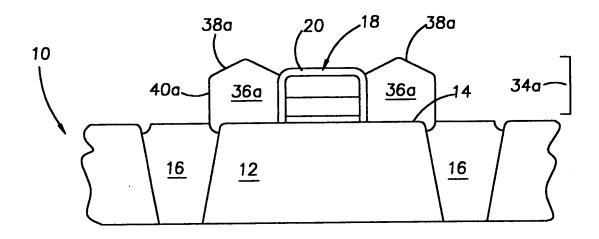
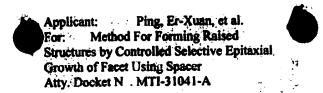


FIG.1B



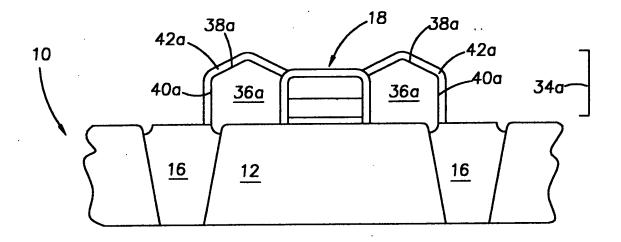


FIG.1C

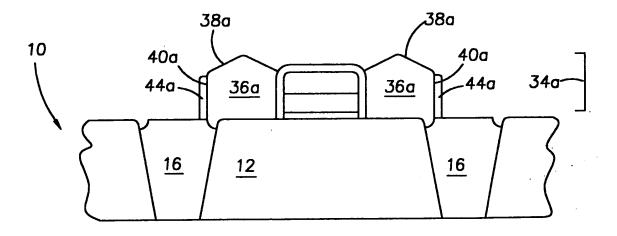
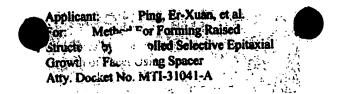


FIG.1D



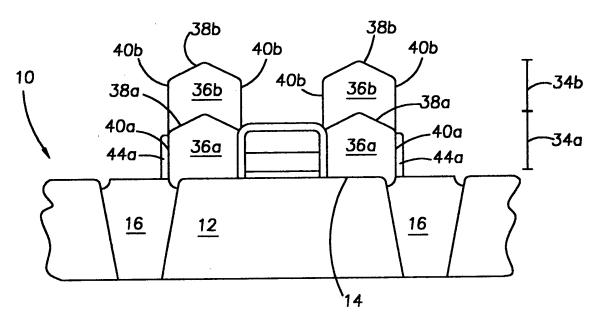


FIG.1E

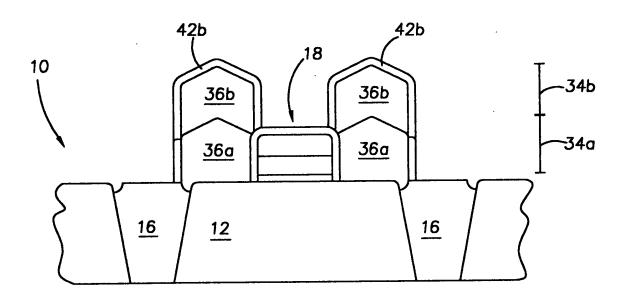
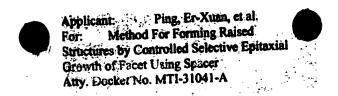


FIG.1F



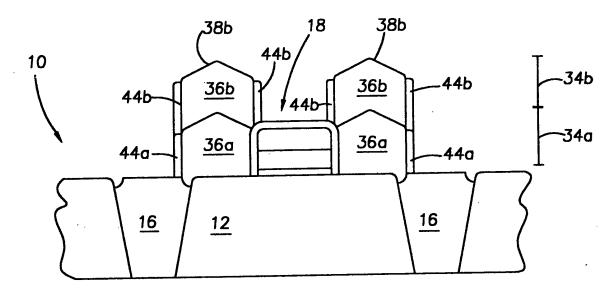
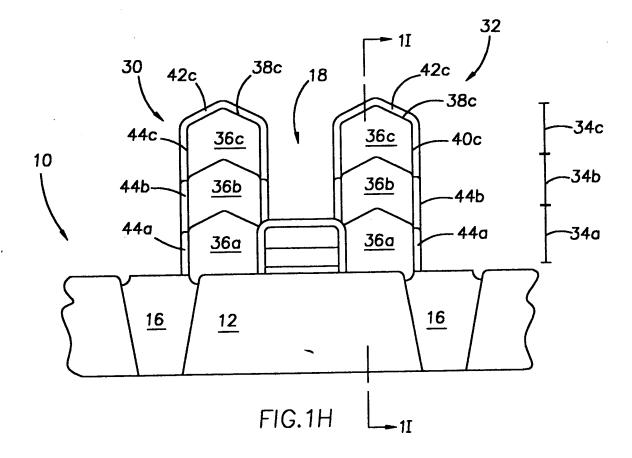


FIG.1G



Applicant:

Ping En Xuan, et al.

For: Method For Porming Raised

octures by Controlled Selective Epitaxial

with f Facet Using Spacer

heavy Docket No. MTI-31041-A

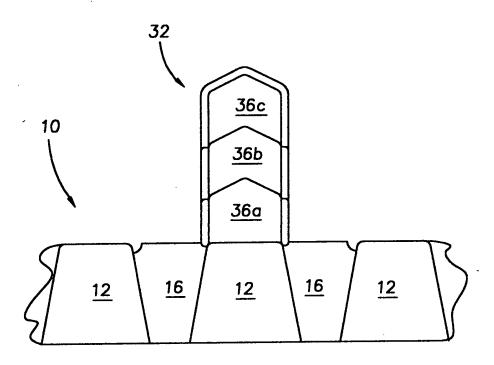
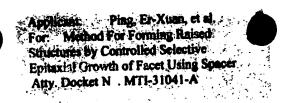


FIG. 1I



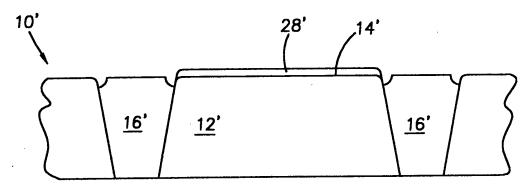


FIG.2A

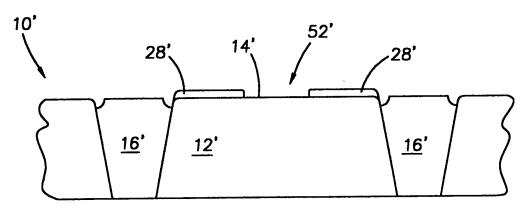


FIG.2B

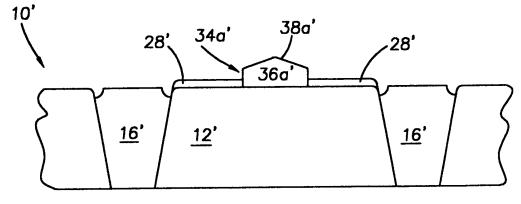
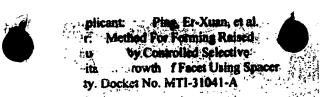


FIG.2C

. . .



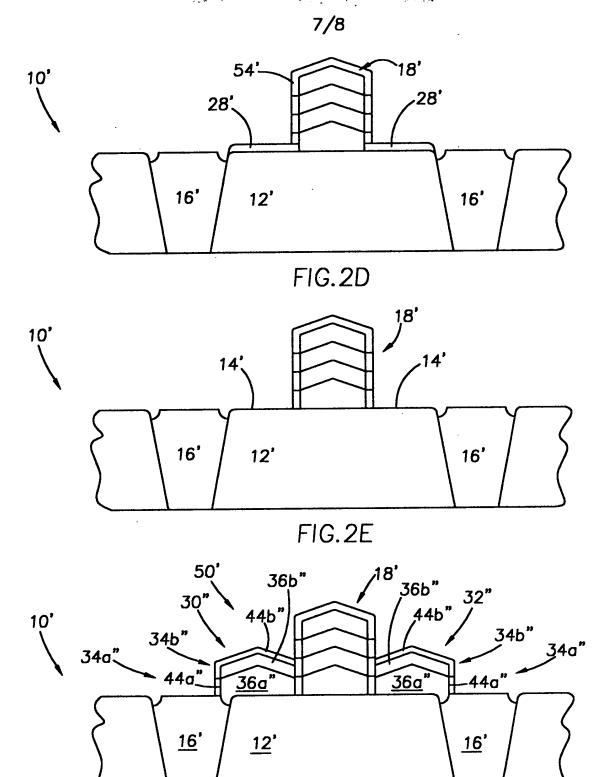


FIG.2F

. . .



Applicants

For: Method For Forming Raised

Structures by Controlled Selective

Epitaxial Growth of Facet Using Spacer

Atty. Docket N . MTI-31041-A

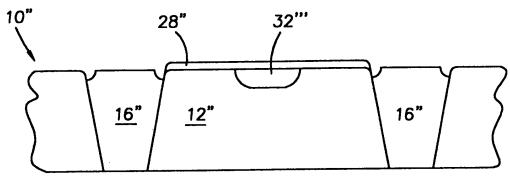


FIG.3A

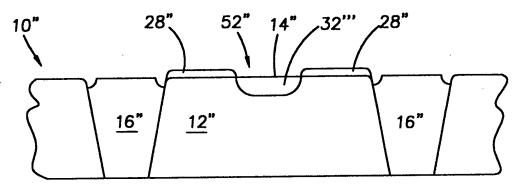


FIG.3B

